## AMENDMENTS TO THE CLAIMS:

The following listing of claims replaces all prior listings, and all prior versions, of claims in the application.

## Listing Of Claims:

(Currently Amended) A <u>vacuum processing apparatus</u>, comprising;
 a plurality of <u>vacuum processing chambers</u> for processing substrates;
 cassette mount tables <u>in an atmosphere</u> for mounting cassettes <u>each storing</u>
 a plurality of substrates to be processed or <u>which have been processed substrates</u>;

a-an atmospheric transfer device for transferring said substrates in the atmosphere being capable of moving at least vertically and of being controlled such that at least one of said substrates to be processed can be taken out of any location in said plurality of cassettes mounted on said plurality of cassette mount tables; and

control means (a) for transferring substrates to be processed from any location in said any one of the cassettes mounted in on the plurality of cassette mount tables in the atmosphere to at least one of the vacuum processing chambers via said atmospheric transfer device and (b) for transferring processed substrates in from said vacuum processing chambers to the respective original locations of the positions within original cassettes, in which the substrates are were stored prior to processing, via said atmospheric transfer device.

(Currently Amended) A <u>vacuum processing apparatus</u>, comprising;
 a plurality of <u>vacuum processing chambers for processing substrates</u>;
 cassette mount tables <u>in an atmosphere for mounting cassettes each storing a</u>

plurality of substrates to be processed or which have been processed-substrates;

a-an atmospheric transfer device for transferring said-substrates in the atmosphere being capable of moving at least vertically and of being controlled such that at least one of said-substrates to be processed can be taken out of any location in said plurality of cassettes mounted on said plurality of cassette mount tables; and

control means (a) for transferring substrates to be processed one by one from any location in said any one of the cassettes mounted in on the plurality of cassette mount tables in the atmosphere to at least one of the vacuum processing chambers via said atmospheric transfer device and (b) for transferring processed substrates in from said vacuum processing chambers to the respective original locations of the positions within original cassettes one by one, in which the substrates are were stored prior to processing, via said atmospheric transfer device.

3. (Currently Amended) A <u>vacuum</u> processing apparatus, comprising:; a plurality of <u>vacuum</u> processing chambers for processing substrates; a plurality of cassette mount tables <u>in an atmosphere</u> for mounting at least one cassette <u>each</u> storing at least one of substrates and at least one cassette storing at least one of dummy substrates;

a-an atmospheric transfer device for transferring said-substrates and said dummy substrates in the atmosphere, being capable of moving at least vertically and of being controlled such that any of said-substrates and any of said-dummy substrates can be taken out of any location in said cassettes mounted on said plurality of cassette mount tables; and

a control means (a) for transferring said-substrates and said-dummy

substrates from any location in any <u>one</u> of said cassettes mounted in <u>said-plurality of</u> on the cassette mount tables in the atmosphere to the at least one of the vacuum processing chambers via said <u>atmospheric</u> transfer device, and (b) for transferring said substrates and said dummy substrates in <u>from</u> said <u>vacuum</u> processing chambers to the <u>respective</u> original <u>locations of the positions within</u> original cassettes, in which the substrates and dummy substrates were stored prior to processing, via said <u>atmospheric</u> transfer device.

4. (Currently Amended) A <u>vacuum processing apparatus</u>, comprising;—:
a plurality of <u>vacuum processing chambers for processing substrates</u>;
a plurality of cassette mount tables <u>in an atmosphere for mounting at least</u>
one cassette <u>each storing</u> at least one of substrates and at least one cassette
storing at least one of dummy substrates;

aan atmospheric transfer device for transferring said-substrates and said dummy substrates in the atmosphere, being capable of moving at least vertically and of being controlled such that any of said-substrates to be processed and any of said dummy substrates can be taken out of any location in said cassettes mounted on said plurality of cassette mount tables; and

a-control means (a) for transferring said-substrates and said-dummy substrates one by one from any location in any one of said cassettes mounted in said-plurality of on the cassette mount tables in the atmosphere to the at least one of the vacuum processing chambers via said atmospheric transfer device, and (b) for transferring said substrates and said dummy substrates from in-said vacuum processing chambers to the respective original locations of the positions within

original cassettes one by one, <u>in which substrates were stored prior to processing</u>, via said <u>atmospheric transfer device</u>.